

Revealing the Cell-Material Interface with Nanometer Resolution by Focused Ion Beam/Scanning Electron Microscopy

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Revealing the Cell–Material Interface with Nanometer Resolution by Focused Ion Beam/Scanning Electron Microscopy

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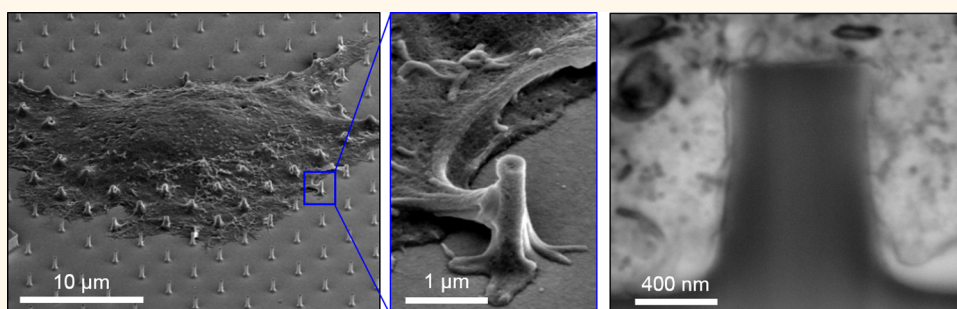
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S Supporting Information



ABSTRACT: The interface between cells and nonbiological surfaces regulates cell attachment, chronic tissue responses, and ultimately the success of medical implants or biosensors. Clinical and laboratory studies show that topological features of the surface profoundly influence cellular responses; for example, titanium surfaces with nano- and microtopographical structures enhance osteoblast attachment and host–implant integration as compared to a smooth surface. To understand how cells and tissues respond to different topographical features, it is of critical importance to directly visualize the cell–material interface at the relevant nanometer length scale. Here, we present a method for *in situ* examination of the cell–material interface at any desired location, based on focused ion beam milling and scanning electron microscopy imaging to resolve the cell membrane-to-material interface with 10 nm resolution. By examining how cell membranes interact with topographical features such as nanoscale protrusions or invaginations, we discovered that the cell membrane readily deforms inward and wraps around protruding structures, but hardly deforms outward to contour invaginating structures. This asymmetric membrane response (inward *vs* outward deformation) causes the cleft width between the cell membrane and the nanostructure surface to vary by more than an order of magnitude. Our results suggest that surface topology is a crucial consideration for the development of medical implants or biosensors whose performances are strongly influenced by the cell-to-material interface. We anticipate that the method can be used to explore the direct interaction of cells/tissue with medical devices such as metal implants in the future.

KEYWORDS: cell–material interface, nanostructures, scanning electron microscopy, focused ion beam, ultrathin resin plasticization

Many biological applications and biomedical devices require direct contact between cells and nonbiological materials.¹ In the case of medical implants, the cell-to-material interface is a key determinant for successful device integration with surrounding tissues, providing mechanical support and minimizing host foreign body responses.^{2–4} Extensive clinical and laboratory studies have shown that

surface topologies of nonbiological materials can significantly affect cellular and tissue responses. For example, titanium implants having a rough surface perform much better than

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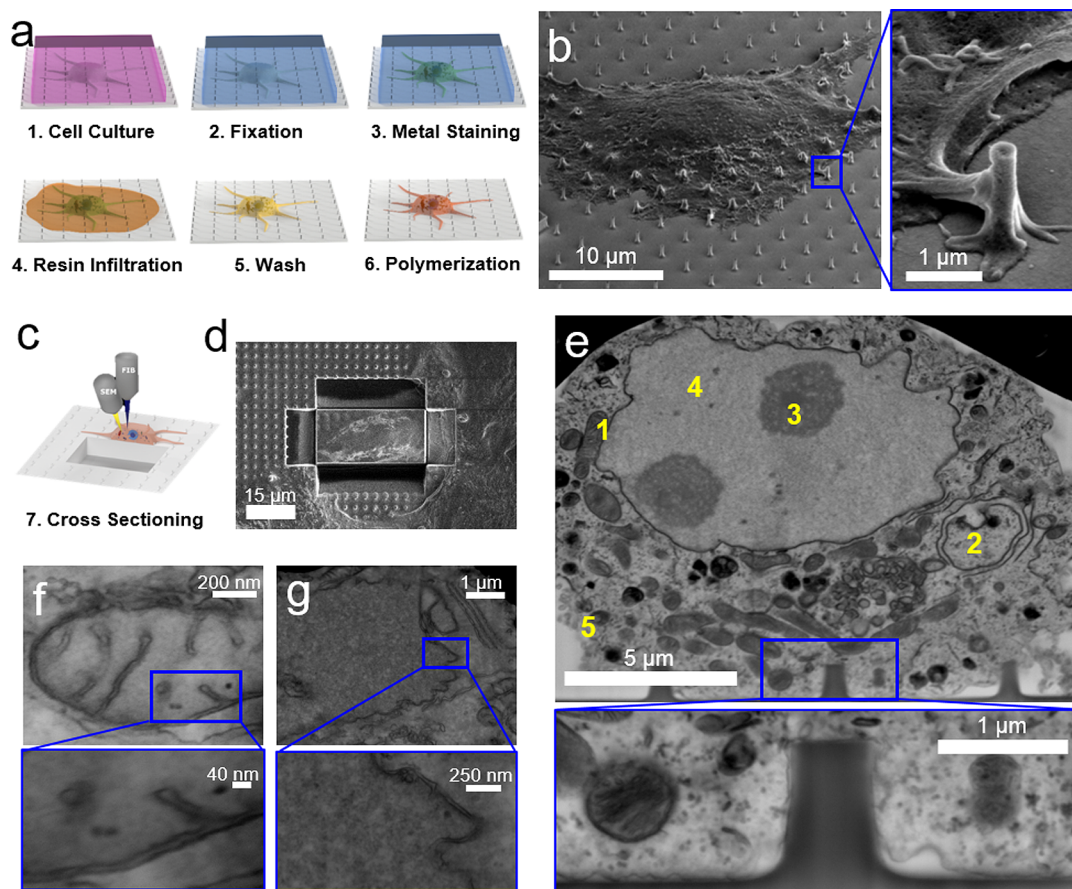


Figure 1. Imaging the cell-to-material interface by FIB/SEM. (a) Schematics of the sample preparation procedure by thin-layer resin plasticization with contrast enhancement. (b) SEM image of a plasticized HL-1 cell on a quartz substrate with nanopillars showing that extracellular resin is removed and the cell morphology is clearly visible. The inset shows that the membrane protrusions in contact with a nanopillar are well preserved. (c) Schematics and (d) experimental results of using FIB milling to cut trenches through the cell and the substrate and open up the interface. (e) SEM image of the interface after FIB milling revealing intracellular compartments and organelles such as mitochondria (1), intracellular membranes (2), nucleoli (3), nucleus (4), and cellular membrane (5). Inset: At the interface between the cell and the quartz substrate, the plasma membrane is shown to warp around a vertical nanopillar. Intracellular structures and local curvatures on the plasma membrane resembling clathrin-mediated endocytosis events can be identified. (f, g) Zoomed-in FIB-SEM images of mitochondria (f) and nuclear envelope (g). The insets clearly resolve the inner and outer membranes and interstitial space. Figures e–g have been acquired from backscattered detectors (voltage: 5–10 kV, current: 0.64–1.4 nA), tilt is 52°, and original images are black–white inverted.

39 those having a smooth surface for osteoblast attachment, host–
 40 implant integration, and the overall success of the implant.^{1,5} At
 41 the cellular level, surfaces with nano- and micrometer
 42 topographical features have been shown to actively affect cell
 43 behavior such as stimulating stem cell differentiation,⁶
 44 enhancing osteoblast maturation,⁷ and regulating macrophage
 45 activity.⁸ In this context, understanding how cells interact with
 46 different features on the material surface is essential to study
 47 how surface topologies regulate cell signaling, guide cell
 48 migration, and control stem cell differentiation.^{9–11}

49 The most critical feature of the cell-to-material interface is
 50 the cleft between the cell membrane and the material surface,
 51 usually in the range of 50–200 nm for flat surfaces.^{12–14}
 52 Sophisticated optical techniques have been developed to
 53 measure the cleft distance, such as fluorescence interference
 54 contrast (FLIC) microscopy,^{15–17} surface-generated structured
 55 illumination microscopy, and variable incidence angle FLIC
 56 microscopy (VIA-FLIC¹⁸). However, these interference-based
 57 techniques are limited to smooth and reflective surfaces and are
 58 not suitable for surfaces with topological features. Transmission
 59 electron microscopy (TEM) is the most widely used method to

60 directly visualize membrane structures at the nanoscale.^{13,14,19}
 61 However, TEM requires sectioning the sample into ultrathin
 62 slices (<100 nm thickness) with mechanical knives, a procedure
 63 not compatible with a variety of substrate materials. For this
 64 reason, the support material underneath the cells has to be
 65 removed and the removal process by chemical or physical
 66 treatment is often not feasible; even if feasible, the procedure is
 67 challenging and can induce structural artifacts at the inter-
 68 face.^{13,20}

69 A combination of focused ion beam (FIB) and scanning
 70 electron microscopy (SEM) constitutes an alternative approach
 71 for *in situ* imaging interfaces of any material and any desired
 72 location.²¹ However, using FIB-SEM to examine the cell-to-
 73 material interface is severely limited by the lack of contrast of
 74 biological specimens and the sponge-like intracellular defects
 75 induced by hard drying procedures.^{22–24} Resin-embedding
 76 preparation with heavy metals allows the visualization of
 77 intracellular structures even in the proximity of nanostruc-
 78 tures,^{25,26} but the resin matrix around the cells does not allow
 79 any visualization of the entire cell unless a 3D reconstruction of
 80 the whole specimen is performed. Recently, thin-layer resin

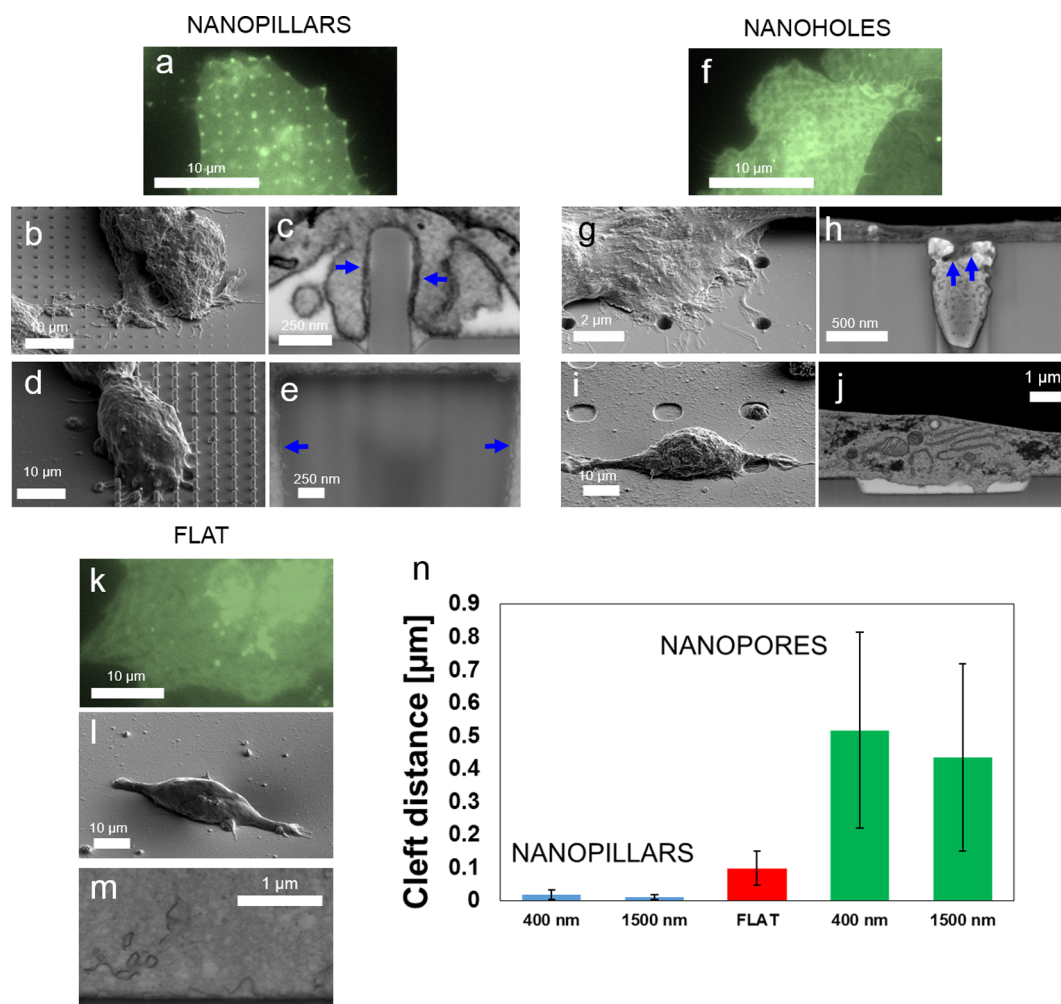


Figure 2. Surface topology drastically affects the cleft distance between the cell membrane and the material surface. (a, f, k) CAAX-GFP transfected cells in green on nanopillars (a), nanopores (f), and flat surface (k) showing accumulation (bright spots) of nanopillars and uniform distribution of nanopores and flat surface. (b, d, g, i, l) SEM of plasticized HEK cells on nanopillar arrays (b, d), nanopore arrays (g, i), and a flat surface (l). (c, e, h, j) FIB cross sections revealing that the plasma membrane wraps tightly around nanopillars with 400 nm (c) and 1500 nm diameter (e), while it mostly grows on top of nanopores of about 400 nm in diameter (h) and tentatively grows inside the nanopore of about 6 μm diameter but remains far away from the surface in most places (j). (m) FIB cross section of a cell on a planar silicon surface showing the membrane-to-material contact at the interface. (n) Direct measurements showing that nanopillars reduce the cleft distance as compared to flat surfaces, while nanopores drastically increase the cleft distance.

81 embedding methods have been developed to allow the
 82 visualization of cells on microstructures,^{24,27,28} but the contrast
 83 of the resulting samples is still too low to clearly resolve the
 84 membrane-to-material interface at the nanoscale. To date, there
 85 is no method that can reliably resolve the plasma membrane in
 86 proximity to nano- and microstructures and thus to measure
 87 the cleft distance between the cell membrane and the material
 88 surface. Therefore, the question of how surface topology affects
 89 the cleft distance remains largely unexplored.

90 In this work, we present a FIB-SEM method that can
 91 precisely resolve the cell-to-substrate interface with 10 nm
 92 resolution. At the core of our FIB-SEM method is a sample
 93 preparation method based on controlled thin-resin plasticiza-
 94 tion of adherent cells with heavy metal staining. Unlike the
 95 usual hard drying methods, this procedure embeds cells in a
 96 thin plastic layer, which not only preserves the subcellular
 97 structures but also provides a solid support for the subsequent
 98 FIB milling.

RESULTS AND DISCUSSION

99
 100 The thin-layer plasticization method includes five major steps: 100
 cell fixation, heavy metal staining, resin infiltration, extracellular
 101 resin removal, and resin polymerization (Figure 1a). Specifi- 101
 cally, mammalian cells cultured on the desired substrate are 102
 fixed by glutaraldehyde to cross-link intracellular structures (*i.e.*, 102
 proteins) so that they can withstand the subsequent staining 103
 and embedding processes without altering the interstitial space 103
 between the membrane and the material surface.^{29,30} After 104
 fixation, the cells are treated with osmium- and uranium-based 105
 staining series (RO-T-O procedure^{31,32} and *en bloc* staining; see 105
 Experimental Procedure for details), a critical step to provide 106
 high contrast to membrane and protein structures. Then, cells 106
 are infiltrated with liquid epoxy-based resin. Traditional resin- 107
 embedding procedures for TEM typically result in a 2–5-mm- 107
 thick polymer block, preventing the visualization of the whole- 108
 cell morphology. In our method, after resin infiltration and 108
 before resin polymerization, a resin-removal step is introduced 109
 that strips off the excess extracellular resin by first draining and, 109
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118 then, flushing the sample with ethanol. This step thins down
119 the resin coating outside the cell membrane to tens of
120 nanometers while maintaining a stable intracellular resin
121 embedding.²⁴ The final step involves curing the liquid resin
122 to a thin layer of plastic with cells embedded inside. Since
123 extracellular resin is largely removed, cell topography and
124 membrane protrusions in contact with the underlying substrate
125 are clearly visible under SEM. Figure 1b shows a resin-
126 embedded HL-1 cell cultured on a quartz substrate with arrays
127 of nanopillars, and Supplementary S1 shows resin-embedded
128 PC12 cells and primary cortical neurons cultured on flat glass
129 substrates, where fine features of the cell membrane are well
130 preserved.

131 Samples prepared *via* thin-layer plasticization are directly
132 mounted on FIB-SEM for *in situ* examination of the cell-to-
133 substrate interface. For this purpose, we first examine a large
134 sample area by SEM to identify locations of interest, such as
135 places where cell membranes are in contact with topological
136 features such as nanopillars. Once a desired area is located, it is
137 coated with a thin layer of platinum to prevent sample damage
138 during the next FIB milling step (see Experimental Procedure
139 and Supplementary S2). Then, a high-energy gallium ion beam
140 (acceleration current of 0.74 nA) is focused on the sample to
141 cut through the platinum protection layer, the cell-embedded
142 thin plastic layer underneath, and at least 1 μm deep into the
143 substrate. This process is repeated to remove material and
144 opens up a vertical surface (Figure 1c,d). Then, a low-current,
145 e.g., 80 pA, ion beam is used to remove redeposited material
146 and polish the cross section. This step is critical for limiting the
147 well-known curtaining phenomena and ion-induced structural
148 damage at the interface.³³ SEM visualization of the cross
149 section clearly shows intracellular structures as well as the
150 interface between the cell membrane and the substrate (Figure
151 1e). Unlike previous FIB-SEM images that usually contain
152 sponge-like structures with no discernible subcellular struc-
153 tures,^{24,27,34} our FIB-SEM images show very clear subcellular
154 structures such as the cell membrane, the nucleus, nucleoli, the
155 nuclear envelope, mitochondria, and intracellular membranes.
156 We note that the resin wash step of the thin-resin plasticization
157 procedure needs to be carried out gently to avoid over-removal
158 of the resin, which can cause cracks in the cell membrane and
159 intracellular space. For the heavy metal staining step, either
160 overstaining or understaining results in poor structural contrast
161 and lower resolution, similar to TEM samples. All FIB-SEM
162 images are black-and-white inverted. Original images are shown
163 in Supplementary S2.

164 To determine the resolution of our FIB-SEM method, we
165 have examined a group of well-characterized cellular compart-
166 ments using high-magnification SEM imaging. Figure 1f shows
167 a mitochondrion with clearly resolved inner and outer
168 membranes (~ 10 nm distance) as well as the cristae structures.
169 Figure 1g shows the structure of a nuclear envelope with well-
170 distinguishable inner and outer membranes, which are
171 separated by an interstitial space of about 20 nm. Endoplasmic
172 reticulum (ER) structures as parallel running membranes can
173 be seen in the vicinity of the nucleus, and the associated small
174 granules attached to the membrane of the ER likely are
175 ribosomes (Supplementary S3). Other intracellular structures
176 such as multivesicular bodies and intracellular membrane can
177 also be resolved in Supplementary S3. Furthermore, a high-
178 magnification SEM image of the cell–substrate interface clearly
179 reveals that the plasma membrane is very close to the flat

substrate surface and contours around local nanopillar features
(Figure 1e, inset). 180 181

The development of this FIB-SEM method allows us to
quantitatively address the question of how different surface
topographies affect the cell–substrate cleft distance. For this
study, we engineer SiO_2 substrates (or Si substrates with a SiO_2
surface layer) with different surface geometries, including
protrusions, invaginations, flat, and other complex structures
(see Experimental Procedure for fabrication details). The
protrusions are vertical nanopillars with diameters or lengths
varying from 200 to 1500 nm, a height of 1 μm , and spacing of
3–5 μm (Figure 2b,d and Supplementary S4). The
invaginations are pores with diameters varying from 200 to
6000 nm, a depth of about 500 nm to 1 μm , and a spacing of 3
 μm (20 μm for the largest pore) (Figure 2g,i and
Supplementary S5). A cell on a flat surface is shown in Figure
2l. The complex structures include nanotubes, nanobars,
irregular nanocones, nanoletters (CUIO), and grooves, and
they are shown in Supplementary S4 and S6. All substrates
were coated with poly-L-lysine or fibronectine to facilitate cell
adhesion. HEK or HL-1 cells were used for the studies. Cells
cultured on different substrates were processed for FIB-SEM
imaging using the aforementioned preparation method. SEM
images of cells cultured on flat, nanopillar, and nanopore
substrates before FIB milling show healthy and spread cell
morphology (Supplementary S7). 182 183 184 185 186 187 188 189 190 191 192 193 194 195 196 197 198 199 200 201 202 203 204 205

The FIB-SEM imaging reveals drastic differences in how cell
membranes respond to different substrate nanotopologies. For
substrates with protruding structures, the cell membrane
deforms readily and wraps conformably around the surface
topology, as shown in Figure 2c,e and Supplementary S8, for
nanopillars with 400 nm and about 1500 nm diameter,
respectively. For nanopillars of all diameters the cell membrane
is usually within 10–30 nm on average from the substrate
surface. In sharp contrast, for substrates with invaginating
structures, the cell membrane hardly deforms and does not
contour the surface of nanopores or the hollow centers of the
nanotubes (Supplementary S9). For small-diameter pores
(Figure 2h), the cell membrane extends into the pores slightly,
but the cleft distance is usually more than 10 times greater than
that for nanopillars. For nanopores as large as 6 μm in diameter
and 500 nm in depth, the cell membrane is still far away from
the surface (Figure 2j), but some attachment points are created
in the pore. For flat surfaces, the cell membrane remains close
to the surface (Figure 2m). A similar phenomenon is observed
in other complex structures (Supplementary S9). For
protruding structures such as nanobars, CUIO nanoletters,
and nanocones, the cell membrane is very close to the substrate
surface, while for invaginating structures such as grooves, the
cell membrane is far away from the substrate surface
(Supplementary S9). For nanotubes, the cell membrane
wraps tightly around the outside wall of the tube (protruding
structure), while it remains far away from the inner wall of the
hollow center (invaginating structure, Supplementary S9). This
is a surprising result, as previous studies suggest that the cell
membrane is highly deformable and can extend into pits as
small as 50 nm.^{35,36} 206 207 208 209 210 211 212 213 214 215 216 217 218 219 220 221 222 223 224 225 226 227 228 229 230 231 232 233 234 235 236

In order to evaluate the cleft formed between the plasma
membrane and different surface topographies, we systematically
measured the average cleft distance for surfaces with nanopillars
and nanopores with comparable dimensions and flat surfaces
(measurement statistics shown in Supplementary S10). As seen
in Figure 2n, the cleft distance is ~ 100 nm (stdv 50 nm) for the 237 238 239 240 241 242

243 flat surface, which agrees with previous studies.^{12,14} The cleft
 244 distance decreases to ~ 15 nm (stdv 10 nm) for nanopillars,
 245 while it increases to >400 nm for nanopores (stdv 300 nm).
 246 These dramatic changes in the cleft width suggest that the
 247 plasma membrane interacts with protruding and invaginating
 248 surface topologies in fundamentally different ways. In addition,
 249 we calculated the cleft area between the membrane and the
 250 nanostructures for all the investigated nanostructures and nanopillar
 251 types. The cleft index measurement confirms that the cleft area
 252 increases in the presence of nanopores and decreases in the
 253 presence of nanopillars (see [Supplementary S10 and S11](#) for
 254 details).

255 To corroborate the FIB-SEM studies, we also examined how
 256 the plasma membrane interacts with different surface topologies
 257 by fluorescence imaging. At the same time, we simultaneously
 258 probed the distribution of actin filaments, which are well known
 259 to participate in the dynamics and the formation of protrusions
 260 or invaginations on the cell membrane.^{37,38} Cells were
 261 cotransfected with two plasmids, CAAX-GFP, which serves as
 262 a marker for the plasma membrane, and LifeAct-RFP, which is
 263 widely used to visualize F-actin in cells. Fluorescence imaging of
 264 CAAX-GFP confirms that the cell membrane wraps around
 265 nanopillars (bright spots due to projection of the vertical
 266 membrane in [Figure 2a](#)) but not nanopores or flat surfaces
 267 ([Figure 2f,k](#)). LifeAct-RFP imaging shows that F-actin
 268 accumulates strongly on nanopillar locations, but is absent at
 269 nanopores ([Supplementary S12](#)) and flat surfaces (data not
 270 shown). This preliminary result suggests that actin filaments
 271 might be involved in forming the close contact between the cell
 272 membrane and the nanopillars.

273 Next, we examine whether the topological effect for the
 274 interface cleft depends on the chemical composition of the
 275 material. Considering that our FIB-SEM method is applicable
 276 to materials with diverse composition and stiffness, we
 277 compared flat and nanopillar surfaces made of quartz (Young's
 278 modulus ~ 80 GPa) and conductive polymer blend poly(3,4-
 279 ethylenedioxythiophene):polystyrenesulfonate (PEDOT,
 280 Young's modulus ~ 1 GPa). Unlike quartz (shown as the gray
 281 bottom layer in [Figure 2f-i](#)), PEDOT is conductive and
 282 scatters electrons strongly (shown as the black bottom layer in
 283 [Figure 3b](#)), which reduces the effective contrast of the
 284 biological sample. Despite this, the FIB-SEM image in [Figure](#)
 285 [3b](#) (cells before cut shown in [Figure 3a](#)) still clearly resolves the
 286 cell membrane–surface gap, achieving the first cross section
 287 visualization of cells on the PEDOT surface. Here, we
 288 measured the effective distance of the plasma membrane
 289 from the surface. The cell membrane is seen in close contact
 290 with the flat PEDOT surface, and the average cleft distance is
 291 measured to be 89 ± 73 nm (stdv), similar to the cleft distance
 292 for the flat quartz surface at 98 ± 52 nm (stdv). Next, we
 293 compared the cleft distances for nanopillar substrates made of
 294 quartz and covered with a thin layer of PEDOT ([Figure 3c,d](#)).
 295 Our measurements show that the average cleft distances for
 296 quartz nanopillars and PEDOT nanopillars are similar ($15 \pm$
 297 2.7 nm and 11 ± 4.1 nm, stdv) but much smaller than that for
 298 the flat surfaces. The statistical details of these measurement are
 299 shown in [Supplementary S10](#).

300 Finally, we explored the capabilities of the FIB/SEM method
 301 for volumetric imaging and multiangle imaging. FIB-SEM
 302 allows repetitive milling and imaging, allowing the investigation
 303 of a volume of interest ([Figure 4a](#)). We used low current (e.g.,
 304 80 pA) for sequential FIB milling, which achieves a slice
 305 thickness of about 20–40 nm and well beyond the capability of

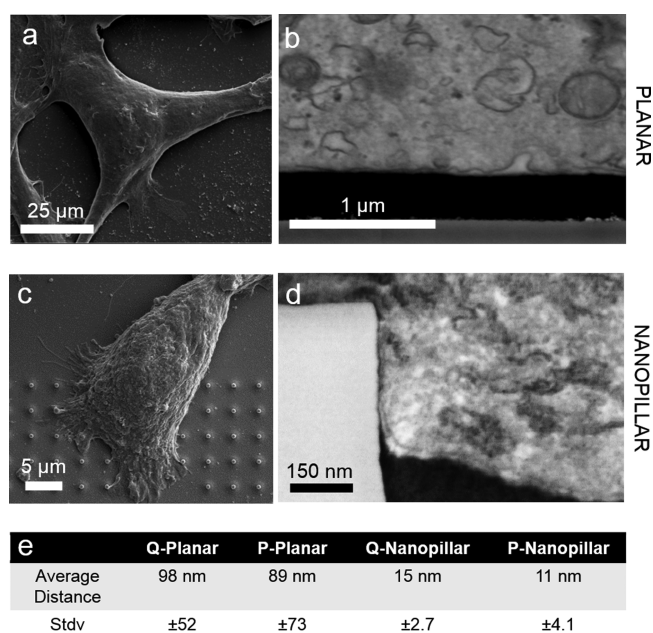


Figure 3. Comparison of quartz and PEDOT surfaces shows that the cleft distance is mainly determined by surface topologies. (a) SEM image of a plasticized HL-1 cell on planar PEDOT. (b) FIB cross section revealing the plasma membrane and local ruffling on the planar PEDOT surface. (c) SEM image of a plasticized HL-1 cell on quartz nanopillars covered with a thin layer (10–20 nm) of PEDOT. (d) FIB cross section revealing the close contact of the plasma membrane to the PEDOT superficial layer on the nanopillar. (e) Quantitative analysis of the average cleft values and the corresponding standard deviation calculated for quartz (Q) and PEDOT (P) substrates with planar and nanopillar surfaces showing that cleft values are comparable for the same structures but different materials.

mechanical slicing by means of ultramicrotomes (70–200 nm).³⁰⁶
 307 [Figure 4b,c](#) show two representative cross sections of the same
 308 cell (shown in [Figure 4a](#)) interacting with two different lines of
 309 nanopillars. By sequentially imaging a set of 72 sequential
 310 sections, we reconstructed a 3D intracellular space and its
 311 interaction with nanopillars using a segmented 3D reconstruction
 312 method ([Figure 4d](#), [Supplementary Movie 1](#)). In particular,
 313 we modeled the 3D morphology of the nuclear envelope,
 314 nucleoli, and the nonadherent cellular membrane domain,
 315 which were individually constructed and overlaid on the
 316 remaining structures, as shown in [Figure 4e](#). The nuclear
 317 envelope appears to be bent upward on top of a nanopillar by
 318 as much as 800 nm ([Figure 4f](#)), agreeing well with our previous
 319 observation by TEM.

320 Unlike the ultramicrotome sectioning method, which slices
 321 materials sequentially in only one direction, the FIB-SEM
 322 method is highly versatile and allows sectioning of the same
 323 sample with different directions at multiple locations. This
 324 capability is often important for cells with protrusions such as
 325 neurons. Primary cortical neurons from embryonic rats were
 326 cultured on a quartz substrate with arrays of solid nanopillars.
 327 After 5 days of culturing *in vitro*, neurons were fixed and
 328 processed for FIB-SEM imaging as described earlier. The SEM
 329 image in [Figure 4g](#) (inset) shows a neuron cell body together
 330 with multiple neurites growing out from the cell body. We first
 331 identified four regions of interest from the SEM image: the cell
 332 body, neurite-1, neurite-2, and neurite-3. Then, after coating a
 333 layer of Pt, FIB milling was used to cut open the interfaces 333

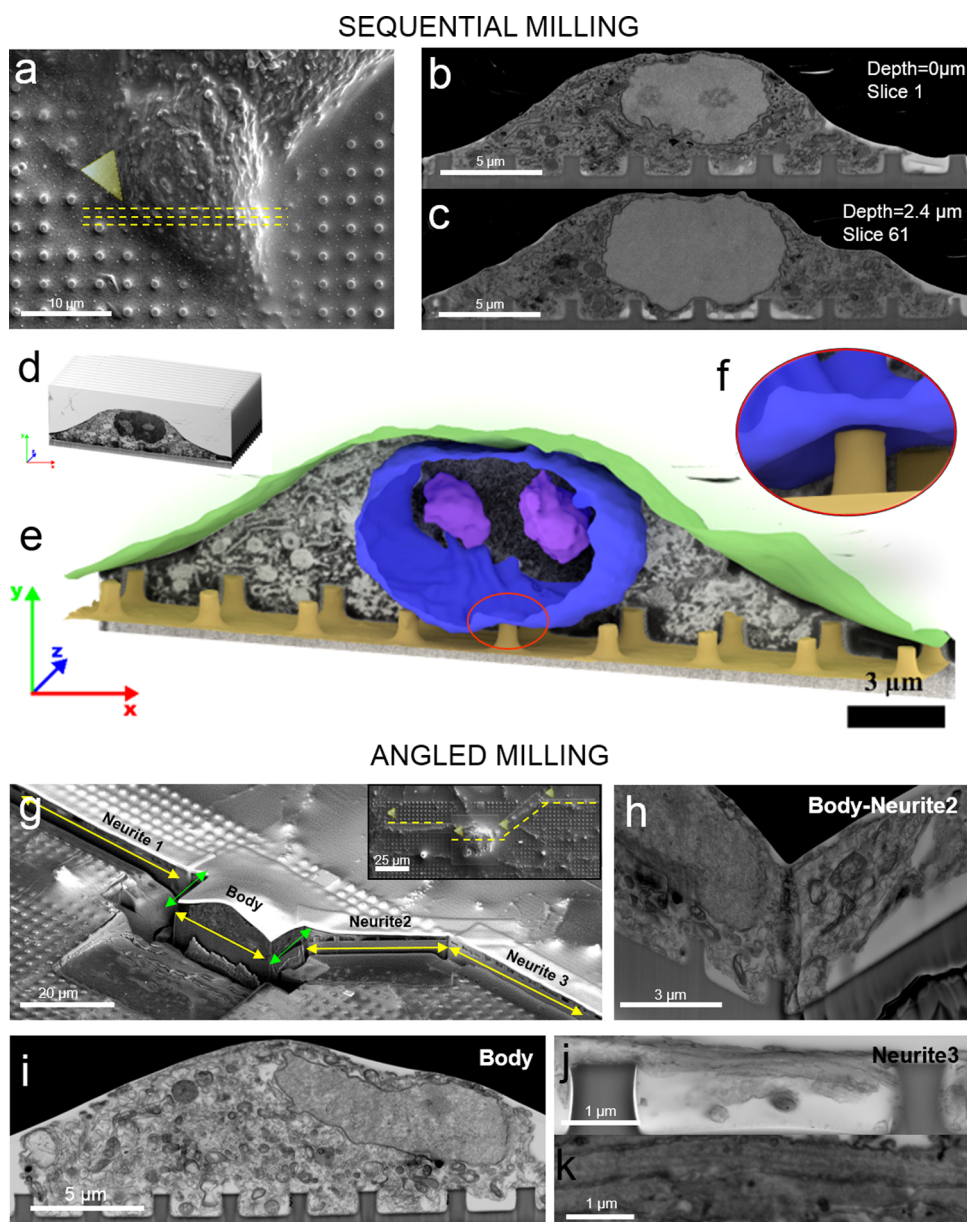


Figure 4. FIB-SEM for sequential volumetric imaging and multiangled imaging. (a) SEM image of a plasticized HL-1 on nanopillars where yellow dashed lines indicate the region of interest for the sequential milling. (b, c) SEM images of two exemplary slices from a stack of 78 slices at two different pillars' lines. (d–f) Images collected in the stack were assembled, segmented, and analyzed. Automated 3D reconstruction of the top membrane and the nuclear envelope overlaid on the SEM background image. Reconstruction shows that the nuclear envelope is deformed upward by a nanopillar. (g) FIB milling of a neuron where yellow arrows indicate the regions of interest and green lines indicate the connecting regions (the inset shows a SEM image of the same neuron before FIB milling). (h) FIB-SEM image of the body–neurite 2 connecting region opened at a 90-degree angle. (i) FIB-SEM image of the neuronal body on a line of nanopillars. (j) FIB-SEM image of neurite 3 on top of nanopillars. (k) Zoomed-in image of neurites revealing multiple longitudinally oriented microtubules parallel to the direction of the neurite.

334 along six connecting lines (yellow arrowed lines corresponding
 335 to four regions of interest and green arrowed lines being the
 336 connecting lines in Figure 4g). FIB-SEM imaging of the cell
 337 body shows the nucleus, a large number of intracellular
 338 organelles, and the plasma membrane wrapping around the
 339 nanopillars (Figure 4i). By multiangle milling, FIB-SEM also
 340 offers the advantage of examining a location from multiple
 341 directions, as shown by the 90-degree intersection between
 342 neurite-2 and the cell body (Figure 4h). The cross section of
 343 neurite-3 is shown in Figure 4j, which illustrates a neurite
 344 attached to the top and the side of two nanopillars. A magnified

image of a neurite reveals multiple longitudinally orientated
 microtubules parallel to the direction of the neurite (Figure 4k),
 comparable in morphology to those investigated by TEM.^{40,41}

CONCLUSIONS

We demonstrate a FIB-SEM method for imaging the cell-to-
 material interface *in situ*, without removing the substrate. The
 FIB-SEM method has the advantages of examining a large
 sample area, opening up cross sections at any desired location,
 achieving volume reconstruction, and performing multidirectional
 milling. This method achieves a high contrast and

355 resolution at 10 nm and is suitable to investigate the interface
356 between the cell membrane and nonbiological materials. Our
357 study reveals a surprising discovery that the cleft width between
358 the cell membrane and the substrate surface is strongly
359 influenced by the surface topology. As the cell attachment and
360 the membrane-to-material interface strongly influence the
361 performance of medical implants and biosensors, our study
362 suggests that surface topology is a crucial consideration for the
363 development of new materials and devices for biological
364 applications. Furthermore, as the FIB-SEM method is
365 compatible with a variety of substrate materials and top-
366 ographies, we expect that this method can be used for more
367 sophisticated *in vivo* studies such as examining the interfaces
368 between osteoblast and titanium implants. We also expect this
369 FIB-SEM method to be compatible with immunolabeling and
370 genetically encoded EM enhancers.⁴²

371 EXPERIMENTAL PROCEDURE

372 **1. Nanostructure Fabrication, Characterization, and Prep-**
373 **aration. Fabrication and Characterization of Quartz Nanopillars,**
374 **CUIO Structures, Nanobars, and Nanotubes.** Nanostructures (NSs)
375 used in this work were fabricated on a 4 in. quartz wafer using
376 electron-beam lithography (EBL). In brief, the wafer was diced into
377 pieces 2 cm × 2 cm square. After sonication cleaning in acetone and 2-
378 propanol, the pieces were spin-coated with 300 nm of ZEP-520
379 (ZEON Chemicals), followed by E-Spacer 300Z (Showa Denko).
380 Desired patterns were exposed by EBL (Raith150) and developed in
381 xylene. The mask was then created by sputter deposition of 100 nm Cr
382 and lift-off in acetone. NSs were generated by reactive ion etching with
383 CH₃F₃ and O₂ chemistry (AMT 8100 etcher, Applied Materials).
384 Before cell culture, the substrate was cleaned in O₂ plasma and
385 immersed in Chromium Etchant 1020 (Transene) to remove Cr
386 masks. SEM (FEI Nova) imaging was performed on 3 nm Cr
387 sputtered substrates to measure the dimensions of different NSs.

388 **Silicon Nanocones.** A monolayer polystyrene nanosphere (PS)
389 array, which consists of PSs with an average diameter of 3 μm, was self-
390 assembled on glass-based silicon substrates with the Langmuir–
391 Blodgett method. To control the effective intervals between the
392 formed silicon nanopillars, a reactive ion etching process with oxygen
393 (O₂) as an etching gas was then followed to shrink the PSs (with a
394 final diameter of 1 μm). Silicon nanocones were last formed on glass
395 substrates by introducing chlorine (Cl₂) and hydrogen bromide (HBr)
396 gases to reactive-ion-etch the silicon materials exposed to the plasma.

397 **Quartz Nanopillars with PEDOT:PSS Cover Layer.** Fused silica
398 glass substrates were cleaned using a standard soap, acetone, 2-
399 propanol sonication sequence. Poly(3,4-ethylenedioxythiophene)
400 polystyrenesulfonate (PEDOT:PSS) (Heraeus, Clevis PH 1000)
401 solution in water was doped with 5 wt % ethylene glycol (EG), 0.1 wt
402 % dodecyl benzenesulfonic acid (DBSA) as a surfactant, and 1 wt %
403 (3-glycidyloxypropyl)trimethoxysilane (GOPTS) as a cross-linking
404 agent to improve film stability. EG, DBSA, and GOPS were all
405 obtained from Sigma-Aldrich. After spin-coating at 1000 rpm for 2 min
406 the films were baked at 120 °C for 10 min.

407 Furthermore, the nanopillar substrates were cleaned using an
408 oxygen plasma etch and the standard acetone 2-propanol sequence
409 without ultrasonication to protect the pillars. A similar PEDOT:PSS
410 solution was spin-coated at 3000 rpm for 2 min and subsequently
411 baked for 10 min at 120 °C to create a uniform film covering the
412 pillars.

413 **Nanopores.** A 500 μm thick (100) silicon wafer was used for the e-
414 beam writing. The sample was spin-coated with 300 nm of negative
415 electron-sensitive resist Ma-N 2403 (MicroChem Corp.) and then
416 baked at 100 °C for 4 min. The pattern was written using an e-beam
417 lithography system (NanoBeam nB5) at 80 kV and was developed in
418 Ma-D 525 developer (Microchem Corp.). A 50 nm layer of Cr metal
419 was deposited using e-beam evaporation for mask creation. After liftoff,
420 nanopores were created on the silicon wafer, defined by a Cr mask,

and etched using an ICP-GSE200 etcher (North Microelectronics). 421
Finally, the Cr mask was removed by concentrated hydrochloric acid. 422
Silicon Grooves. The samples were manufactured at the Molecular 423
Foundry at Lawrence Berkeley National Laboratory under contract 424
DE-AC02-05CH11231. 425

FIB-Based Procedure. Quartz substrates were coated with a 200 nm 426
thick layer of platinum. Nanopores (1.5–3 μm diameter, 3–5 μm 427
pitch) were etched by focused ion beam (dual beam Helios 600i, at 30 428
kV and a current of 40 pA). Afterward, the platinum layer was 429
removed by aqua regia overnight at room temperature. 430

Sample Preparation for Cell Culture. Quartz substrates were 431
treated with piranha solution with sulfuric acid and hydrogen peroxide 432
(Fisher Scientific), in a 7:1 dilution at room temperature overnight. 433
Samples were washed with distilled water, dried, and placed in 70% 434
ethanol in a sterile hood. Samples were washed with sterile distilled 435
water and allowed to dry. After a 15 min UV light exposure, samples 436
were incubated overnight with 0.01% poly-L-lysine (Sigma Life 437
Science) for primary neurons and HEK cell cultures or with 1 mg/ 438
mL fibronectin (Life Technologies) in 0.02% gelatin solution for HL-1 439
cells. COS-7 cells were directly plated on the substrate after 440
sterilization. 441

2. Cell Culture and Transfection. Primary Neurons. Cortices 442
were extracted from rat embryos at embryonic day 18 and incubated 443
with 0.25% trypsin/EDTA (Corning) in a 33 mm Petri dish for 5 min 444
at 37 °C. The tissue-trypsin/EDTA solution was transferred into a 2 445
mL plastic tube. The tissue settled at the bottom of the tube, and 446
leftover trypsin/EDTA was removed. Neurobasal media (Gibco) was 447
supplemented with 1% B27 (Gibco), 0.25% glutaMAX (Gibco), and 448
0.1% gentamycin antibiotic (Gibco). One milliliter of warm media was 449
added, and then the tube was gently swirled by hand. This procedure 450
was repeated five times, and after the last media exchange, the tissue 451
was dissociated until resulting in a cell solution. A total of 80 000 cells 452
were suspended in 3 mL and placed on each substrate. The media was 453
replaced completely 2 h after seeding time. Every second day, half of 454
the media was exchanged with freshly prepared warm (supplemented) 455
Neurobasal media. 456

HL-1 Cells. Confluent HL-1 cells, cultured in a 33 mm Petri dish, 457
were incubated with 1 mL of 0.25% trypsin/EDTA for 5 min at 37 °C. 458
The cell–trypsin solution was transferred into a 15 mL tube, and 2 mL 459
of Claycomb media (Sigma Life Science) supplemented with 10% fetal 460
bovine serum (Sigma-Aldrich), 100 μg/mL penicillin/streptomycin 461
(Sigma Life Science), 0.1 mM norepinephrine (Sigma-Aldrich), and 2 462
mM glutaMAX were added. The cell solution was placed in a 463
centrifuge for 3 min with a rotation of 1300 rpm. The cell pellet was 464
resuspended in 1 mL of media, and 50 μL of the resuspension was 465
plated on each substrate in addition to 3 mL of supplemented media. 466

HEK 293 Cells. HEK 293 expressing channels NaV 1.3 and KIR 2.1 467
were acquired by Adam Cohen laboratory and maintained in DMEM/ 468
F12 (Gibco), 10% FBS (Gibco), 1% penicillin/streptomycin (100 μg/ 469
mL, Gibco), Geneticin (500 μg/mL, Gibco), and puromycin (2 μg/ 470
mL, Fisher Scientific). At 80% confluency, cells were divided, 471
resuspended, and plated on quartz substrates as for HL-1 cells. 472

COS-7 and U2OS Cells. Cells were maintained in DMEM 473
supplemented with 10% fetal bovine serum, and at 90% confluency 474
they were divided as for HL-1 cells and plated on the substrates. 475

CAAX/LifeAct Transfection. U2OS cells were cultured in DMEM 476
medium (HyClone) with 10% fetal bovine serum (Gibco) and 1% 477
penicillin/streptomycin (Invitrogen) at 37 °C in 5% CO₂. Trans- 478
fection was performed using electroporation (Amaxa Nucleofector) 479
with the manufacturer's protocol. U2OS cells were transfected with 480
Lifeact-RFP (transformed bacteria acquired from AddGene) and Caax- 481
GFP and plated on a nanostructured surface for at least 16 h before 482
examination. 483

3. Ultrathin Plastification and RO-T-O Procedure. Substrates 484
with cells were rinsed with 0.1 M sodium cacodylate buffer (Electron 485
Microscopy Sciences) and fixed with 3.2% glutaraldehyde (Sigma- 486
Aldrich) at 4 °C overnight. Specimens were then washed (3 × 5 min) 487
with chilled buffer and quenched with chilled 20 mM glycine solution 488
(20 min). After rinsing (3 × 5 min) with chilled buffer specimens were 489
postfixed with equal volumes of 4% osmium tetroxide and 2% 490

491 potassium ferrocyanide (Electron Microscopy Sciences, RO step) (1 h
492 on ice). Samples were then washed with chilled buffer (3 × 5 min),
493 and the solution was replaced with freshly prepared 1% thiocarbonyl-
494 drazide (Electron Microscopy Sciences, T step) (20 min at room
495 temperature). After rinsing with buffer (2 × 5 min), the samples were
496 incubated with 2% aqueous osmium tetroxide (O step) (30 min at
497 room temperature). Cells were again rinsed (2 × 5 min) with distilled
498 water and then, finally, incubated with syringe-filtered 4% aqueous
499 uranyl acetate (Electron Microscopy Sciences, en bloc step) (overnight
500 4 °C). Cells were rinsed (3 × 5 min) with chilled distilled water,
501 followed by gradual dehydration in an increasing ethanol series (10%–
502 30%–50%–70%–90%–100%, 5–10 min each on ice). The last
503 exchange with a 100% ethanol solution was performed at room
504 temperature. Epoxy-based resin solution was prepared as previously
505 described,²⁴ and samples were infiltrated with increasing concen-
506 trations of resin in 100% ethanol, using these ratios: 1:3 (3 h), 1:2 (3
507 h), 1:1 (overnight), 2:1 (3 h), 3:1 (3 h). Infiltration was carried out at
508 room temperature and in a sealed container to prevent evaporation of
509 ethanol. Samples were then infiltrated with 100% resin overnight at
510 room temperature. The excess resin removal was carried out by first
511 draining away most of the resin by mounting the sample vertically for
512 1 h and, then, rapidly rinsing with 100% ethanol prior to
513 polymerization at 60 °C overnight.

514 **4. Scanning Electron Microscopy Imaging and Focused Ion**
515 **Beam Sectioning. Sample Preparation.** Each sample was glued with
516 colloidal silver paste (Ted Pella Inc.) to a standard stub 18 mm pin
517 mount (Ted Pella Inc.). A very thin layer of gold–palladium alloy was
518 sputtered on the sample before imaging.

519 **SEM Imaging.** Samples were loaded into the vacuum chamber of a
520 dual-beam Helios Nanolab600i FIB-SEM (FEI). For selecting a region
521 of interest, an (electron) beam with an accelerating voltage of 3–5 kV
522 and current of 21 pA to 1.4 nA was applied. For image acquisition of
523 whole cells (*i.e.*, Figure 1b) a secondary electron detector was used.
524 For cross section imaging, a beam acceleration voltage of 2–10 kV was
525 selected, with the current ranging between 0.17 and 1.4 nA, while
526 using a backscattered electron detector (immersion mode, dynamic
527 focus disabled in cross section, stage bias zero), a dwell time of 100 μs,
528 and 3072 × 2048 pixel store resolution. For the sequential sectioning,
529 the function iSPI was enabled in order to slice and acquire an image of
530 the stack every 38.5 nm with 5 kV voltage, 1.4 nA current, and 1024 ×
531 884 resolution.

532 **FIB Sectioning.** Regions of interest were preserved by electron-
533 assisted deposition of a 0.5 μm double platinum layer and ion-assisted
534 deposition of a (nominal) 1 μm thick coating. First, trenches were
535 created with an etching procedure fixing an acceleration voltage of 30
536 kV and currents in the range 9.1–0.74 nA depending on the effective
537 area to remove. A fine polishing procedure of the resulting cross
538 sections was carried out on the sections, with a voltage of 30 kV and
539 lower currents in the range 0.74 nA to 80 pA so that redeposition
540 phenomena in the cross section are very limited.

541 **Image Analysis and 3D Reconstruction.** All images were
542 preprocessed with ImageJ (National Institutes of Health, USA,
543 <http://imagej.nih.gov/ij>). The images of the sequential cross sections
544 shown in Figure 2 were collected as a stack, analyzed, and processed
545 with an open source tool chain based on Python (Python Software
546 Foundation, USA, <http://www.python.org>) scripts and tools. The
547 image stack was cropped, filtered, and down-sampled. The isotropic
548 resolution in *x*, *y*, and *z* amounts to 38.5 nm. The reconstructed data
549 are visualized with Blender (Blender Foundation, The Netherlands,
550 <http://www.blender.org>).

551 **Cleft Distance.** The average cleft distance has been calculated by
552 selecting 10 equally distributed points on the part of the plasma
553 membrane that surrounds the nanostructures. For each point, the
554 distance is measured as the shortest distance between the membrane
555 and the material surface. The number of points, the number of
556 nanostructures, and the number of cells that are used to calculate the
557 average number (and the standard deviations of the mean) are listed in
558 **Supplementary Table S10**. The measurements have been performed
559 with ImageJ.

ASSOCIATED CONTENT

Supporting Information

The Supporting Information is available free of charge on the
ACS Publications website at DOI: 10.1021/acsnano.7b03494.

Movie (AVI)

Ultrathin plasticization of cells on planar substrates,
sectioning procedure, ultrastructure resolution, substrate
geometry of nanopillars and nanocones, substrate
geometry of nanopores, substrate geometry of CUI,
nanobars, nanotubes, and grooves, SEM of cells on a flat
surface and diverse nanostructures, cleft between cells
and flat, nanopillar, and nanopore surfaces, cleft visual-
ization for cells on complex structures, cleft distance, cleft
index, CAAX/ACTIN cotransfection (PDF)

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Notes

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